



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as first class mail in an envelope addressed to Commissioner of Patents and Trademarks, Washington, D.C. 20231 on December 23, 2002.

R. L. Milton
Signature

Applicant : Francis M. Reininger
Application No. : 09/547,790
Filed : April 12, 2000
Title : SPATIALLY MODULATED INTERFEROMETER AND BEAM
SHEARING DEVICE THEREFOR
Grp./Div. : 2882
Examiner : Wang, George Y.
Docket No. : 39260/RAG/C766

AMENDMENT & REQUEST
FOR RECONSIDERATION

Assistant Commissioner for Patents
Washington, D.C. 20231

Post Office Box 7068
Pasadena, CA 91109-7068
December 23, 2002

Commissioner:

In response to the Office action of August 23, 2002, please amend the above-identified application as follows:

In the Claims:

Please amend claims 1-4, 6-22, 24-28, and add new claims 30-35.

1. (Amended) A beam shearing system for shearing an incident beam of light having a chief ray, comprising:
an entrance slit structure having an entrance slit extending in a first direction for receiving a beam of light having a photon flux within a predetermined spectral pass band;
a beam splitter aligned at an angle to the first direction so that the received beam of light is split into two separate beams; and